

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)	PATENT APPLICATION
)	
Inventor: Apostolos Voutsas)	
)	
Serial No.: Not Yet Assigned)	Attorney Docket No.
)	SLA 0592
Filed: Herewith)	
)	
Title: METHOD FOR FORMING)	
SILICON FILMS WITH TRACE)	
IMPURITIES)	
)	

DECLARATION FOR PATENT APPLICATION

As a below named inventor, I hereby declare that my residence, post office address and citizenship are as stated below next to my name; I believe that I am the original, first and sole inventor (if one name is listed below), or the first and joint inventor (if plural names are listed below), of the subject matter which is claimed and for which a patent is sought on the invention entitled,

**METHOD FOR FORMING SILICON FILMS
WITH TRACE IMPURITIES**

the specification of which (check applicable ones):

- is attached hereto;
- was filed with the above-identified "Filed" date and assigned the above-identified "Serial No.:";
- was amended on (or amended through) _____.

I hereby declare that all statements made herein of my own knowledge are true and that all statements made on information and belief are believed to be true, and further that these statements were made with the knowledge that willful false statements and the like so made are punishable by fine or imprisonment, or both, under Section 1001 of Title 18 of the United States Code and that such willful false statements may jeopardize the validity of the application or any patent issuing thereon.

Full name of sole
or first inventor: Apostolos Voutsas

Residence: 10909 SE 18th Street
Vancouver, WA 98664

Post Office Address: Same

Citizenship: United States of America

Inventor's signature:



Date: June 28, 2001
